

MAD workshop report on crystalline Test Mass suspension

F. Travasso on behalf of ET-Test Mass Suspension WP...and many others

ET Annual Meeting – Opatija– 12/11/2025



...a young but very proficient collaboration



List of previous meetings

- ISB Workshop L'Aquila October 2022
- Silicon Workshop Maastricht April 2023
- TMS-CO Workshop Glasgow October 2023
- MAD 2024 Warsaw November 2024
- MAD 2025 Berlin October 2025 (IKZ)

MAD25 Participation

Organized at IKZ, the workshop was a mix of researchers and industry professionals

44 in person attendees ~20 remote attendees



MAD25 Organisers

Iryna Buchovska Robert Menzel

Scientific Committee

Alex Amato
Iryna Buchovska
Elisabetta Cesarini
Margot Henning
Robert Menzel,
Luca Naticchioni
Andrew Spencer
Flavio Travasso





MAD Workshop timetable



Monday 6 October 2025	Tuesday 7 October 2025 _{09:00}	Introduction on Suspension Research	Andrew Spencer
10:00-12:00	9:00-12:00	Max-Born-Saal	09:00 - 09:15
IKZ Lab tour	Suspension	Float zone silicon fibers for suspension application in Einstein Telescope	Dr Iryna Buchovska 🥝
		Max-Born-Saal	09:15 - 09:30
		ET-FIBER: Monocrystalline Silicon Fibre Development for Cryogenic Test Mass Suspensions	Mr Gilles Magain et al.
12:30-17:00	12:30-16:00	Max-Born-Saal	09:30 - 09:45
Substrates	Coatings	Cautions for a correct evaluation of breaking strength measurements	Flavio Travasso 🥝
		Max-Born-Saal	09:45 - 10:00
10:00		Precision Mechanical Loss Measurement & Noise Characterisation: E-TEST Cryogenic Prototy	pe Hemendra Singh 🥝
Cooling away the absorption - Silicon mirror developmen Janis Woehler Development of a Silicon Suspension System for the Ein Maike Kühler Advancing electrochemical micromachining technology f Dr Muhammad Hazak Arshad		Max-Born-Saal	10:00 - 10:15
		Coffee Break	
		Max-Born-Saal	10:15 - 10:45
		Mechanical Dissipation in Maraging Steel at Room Temperature and Very Low Frequency	Matteo Baratti 🥝
		Max-Born-Saal	10:45 - 11:00
Towards Reliable Bonding of Sapphire and Silicon II Alexey Kuzmichev		Sapphire-Based Suspension at ARC-ETCRYO Laboratory: Ongoing Test Campaigns	Dr Emanuele Tofani et al. 🏽 🥝
		Max-Born-Saal	11:00 - 11:15
		Sapphire fibre suspensions for KAGRA and ET with low loss jointing techniques	Jennifer Docherty
Meeting page		Max-Born-Saal	11:15 - 11:30
https://indico.ego-gw.it/event/905/		MAD25: Session 2. Suspensions: Discussion	
Minutes of the workshop https://apps.et-gw.eu/tds/ql/?c=18189		Max-Born-Saal	11:30 - 12:00



Float Zone silicon fibers for suspension application in Einstein Telescope

I. Buchovska¹, B. Scalise¹, M. Scheffler¹, F. M. Kiessling¹, K. Schindler¹, I. Tsiapkinis¹, R. Menzel¹, A. Nela², G. Lacaille², K. Haughian², K. Toland², A. Spencer²

- ¹ Leibniz-Institut für Kristallzüchtung (IKZ)
- ² University of Glasgow









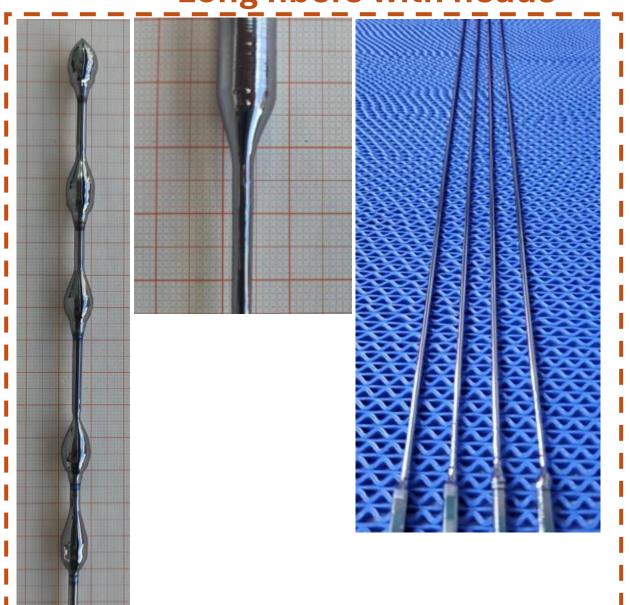
Pedestal growth Float zone growth Crystal HF Inductor Feed Pulling Pulling Melt

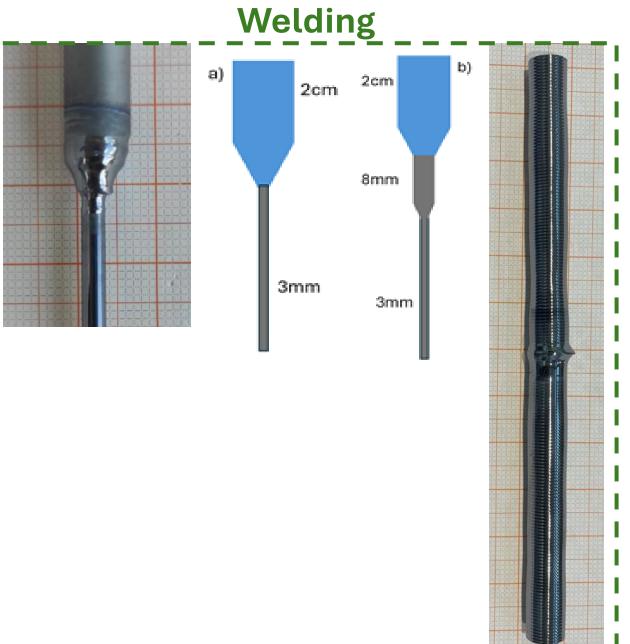


This work was funded by the BMBF, Grant Number 05A23BC1, 07/2023 – 06/2026 "Verbundprojekt 05A23BC1 – 3G-GWD: Gravitationswellen-Teleskop der dritten Generation. Teilprojekt 4"

IKZ Production Long fibers with heads





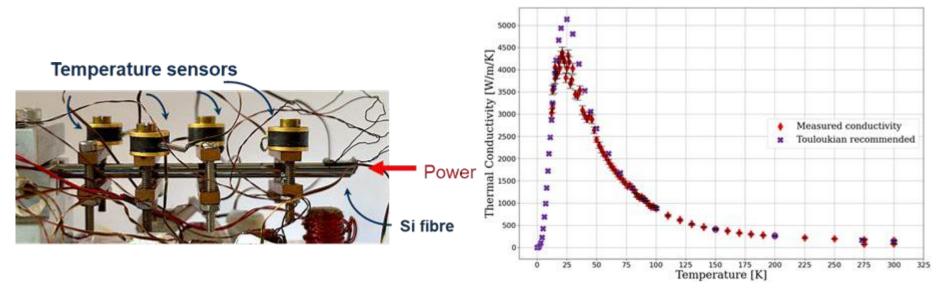






Thermal conductivity Ø 3 mm fiber

- Measured thermal conductivity of Ø 3mm uniform control sample
- o Results within the recommended Touloukian curve [2]
- Growth process preserves the high thermal conductivity of silicon
- Diameter for heat extraction limited case for ET:
 1375 μm (at 15-20K)



[2] Y. S. Touloukian et al. "Thermophysical properties of matter - the TPRC data series (1970); Volume1



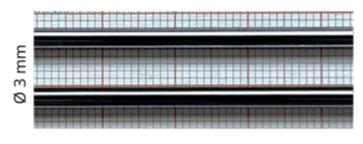
Results on Ø 1 mm Si-fiber growth

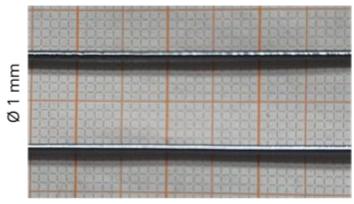
Si-fiber diameter: 1 mm

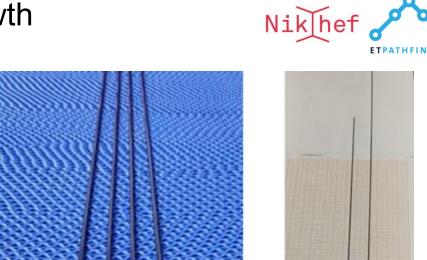
Diameter variation: +/- 0.1 mm

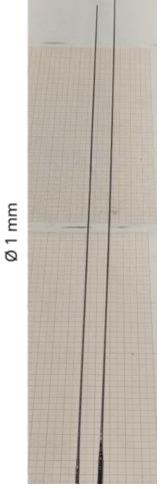
Length: up to 80 cm

Further development for stable and reproducible process is ongoing









3 mm





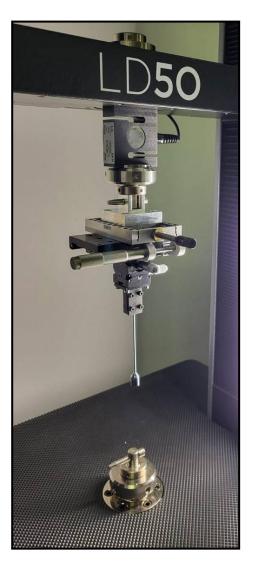
Cautions for a correct evaluation of breaking strength measurements

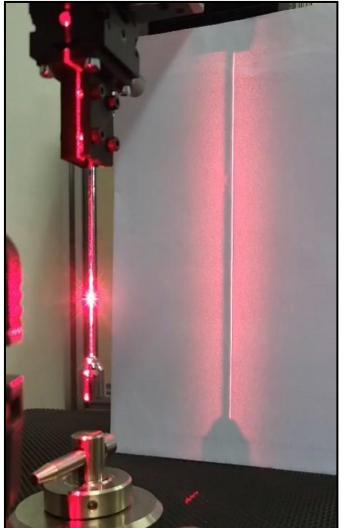
M. A. Dicorato, A. Nela, A. Spencer, F. Travasso



Clamping method

- 1. Temporary fixation of the seed to the micrometric alignment system
- 2. **Vertical fiber alignment**, checking fiber position with laser level
- 3. Positioning the lower clamp so that it embraces the fiber head, without touching the fiber body, and injecting the epoxy resin into the 3D-head housing

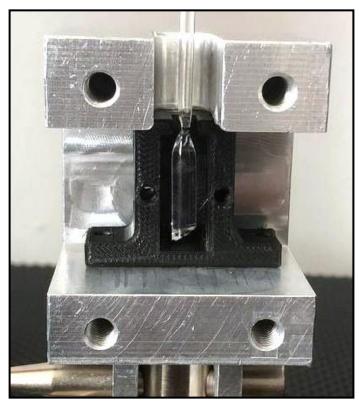






Clamping method

3. Positioning the lower clamp

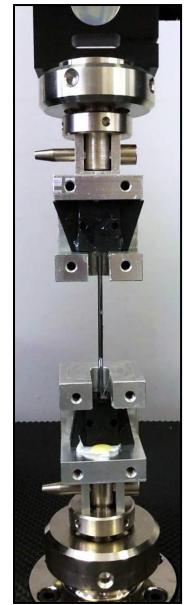


4. Waiting for the resin to cure



5. Repeating the procedure to glue the seed

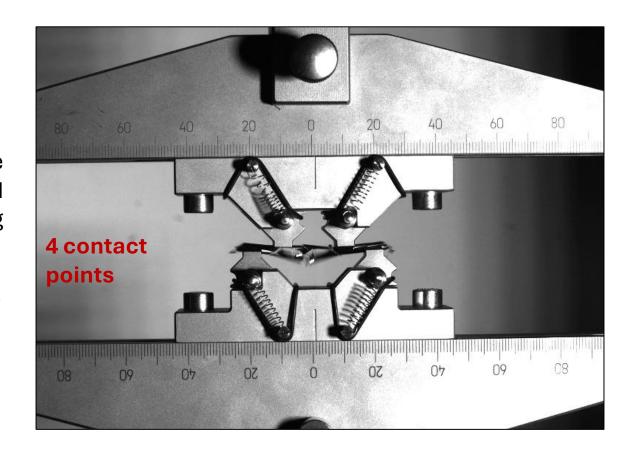


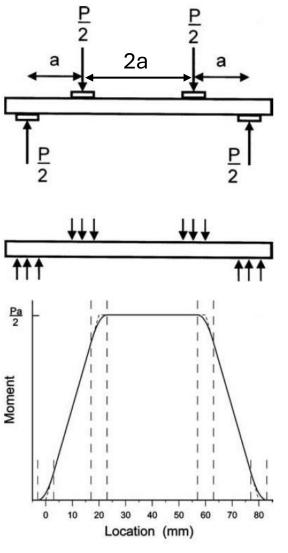


4-point bending method

Maximum stress on a line at the bottom of the rod within the two inner loading points

$$\sigma_{max} = \frac{16Pa}{\pi D^3}$$
 $a = 10 \text{ mm}$
 $D = 3 \text{ mm}$

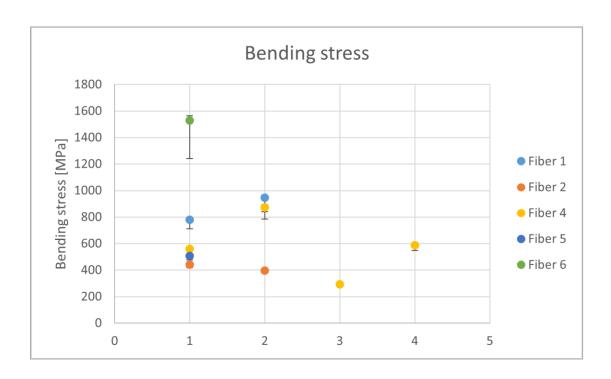


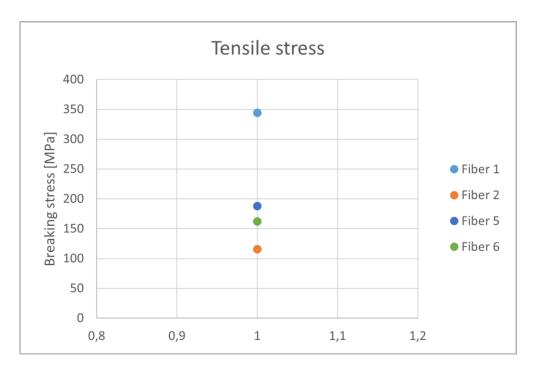


Bending system designed and optimized for cylindrical rods 3 mm thick and 5 cm long, according to the American Society for Testing and Materials standard ASTM C1684-18 2023

Quinn et al., Journal of Testing and Evaluation, 2009

Bending vs tensile results





Considerations

- Stresses in bending are higher than those in tensile
- High variability in general
- Fiber 4: very different values (maybe heterogeneity in the defects)
- Dominant error at high strength: Contact point tangency shift
- The bending and tensile data are consistent for fibers 2,5, and

Future work

- Reduce the cradle size and the roller size to reduce the dominant error
- Increase the number of tested samples to improve the statistics

Clamps

Steel clamp

Thickness: 4,5 cm

E = 200 GPa

 $\rho=7850~\text{kg/m}^3$

v = 0,3

Copper clamp

Thickness: 5,3 cm

E = 128 GPa

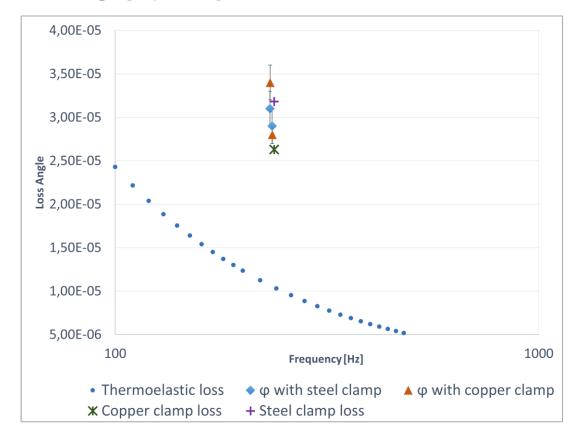
 $\rho = 8960 \text{ kg/m}^3$

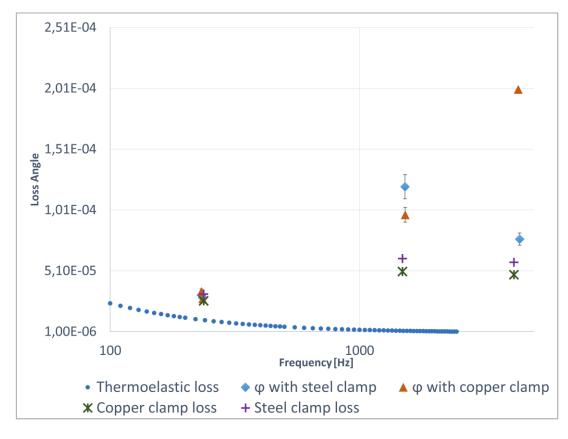
v = 0,34





Results





Considerations

- Clamp is probably the dominant source of dissipation
- Measured loss-angle too high with respect the expected value for silicon at room temperature (10^{-8})

Future work

- Increase clamp thickness
- Cryogenic measurements
- Copper clamp with





MAD25: The ETFIBER Project

Gilles Magain



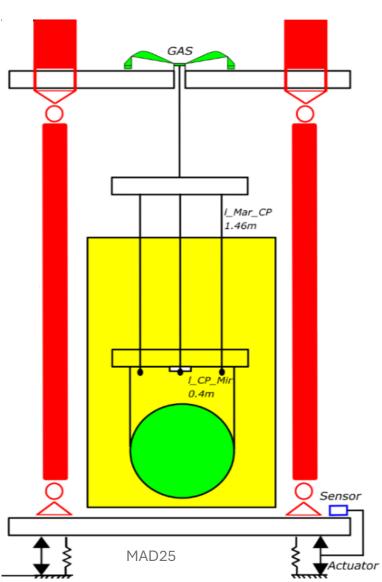
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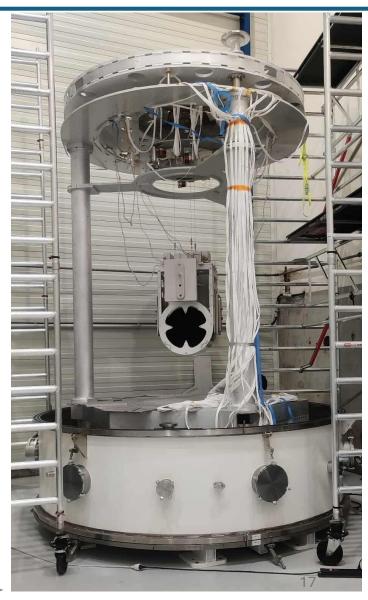
ETEST Prototype



Precision Mechatronics Laboratory

- Test of advanced seismic isolation
- Low seismic noise below 10 Hz
- The goal is to isolate the test mass
- The isolated mass will ultimately be a 100 kg silicon mirror design to operate at cryogenic temperatures (20K)





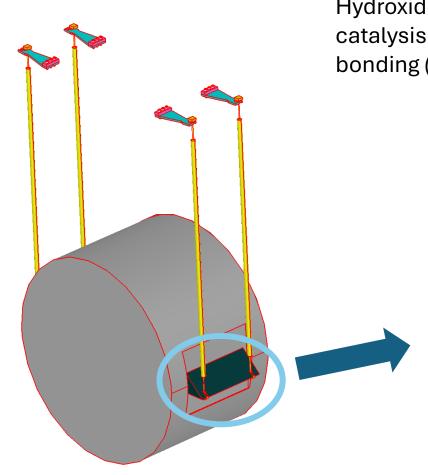
Tension design



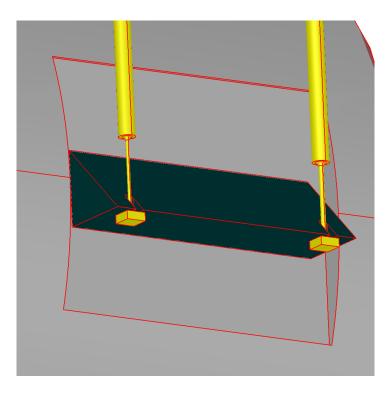


Thinning to gain flexibility:

- Smaller diameter close to the yield point
- Effective stiffness not as low as wanted.

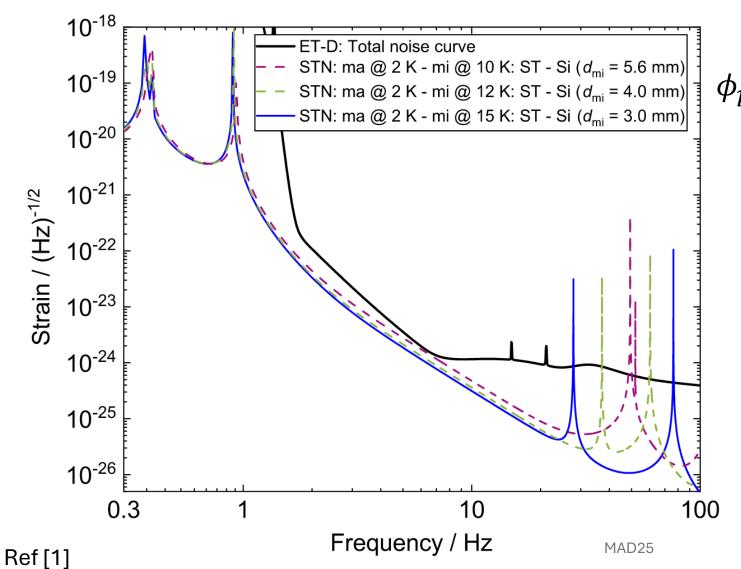


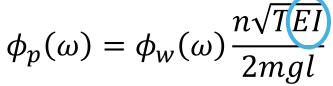
Hydroxide catalysis bonding (HCB)



Thermal noise VS Sensitivity







Ref [4]

The loss angle is proportional to d^2

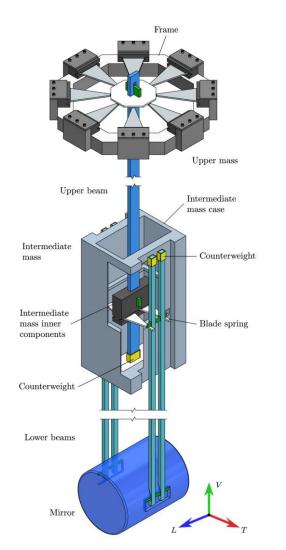
$$I = \pi \frac{d^4}{64}$$

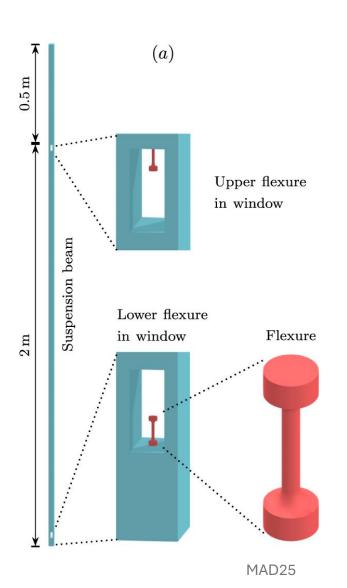
The thermal noise is just below the sensitivity.

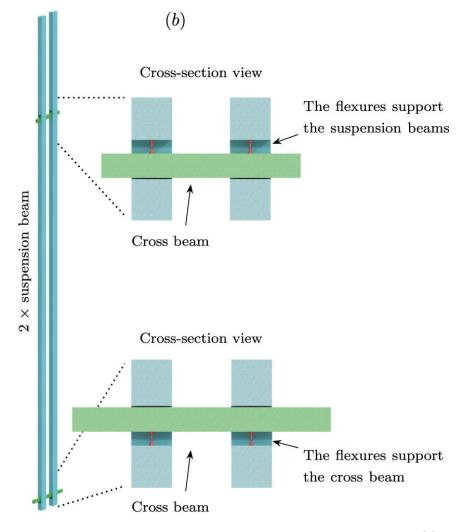
The compressive design











Use of Si Isotope



21

Flexures have short length, but they set the limit of suspension thermal conductivity due to their small diameter



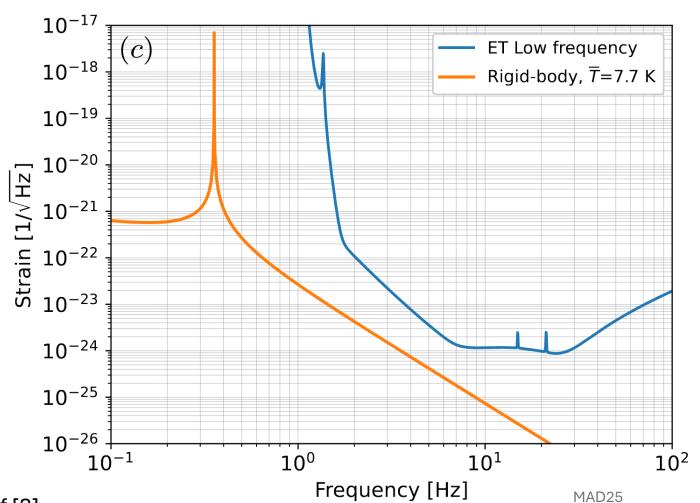
Use of isotopically pure Silicon $^{28}Si \rightarrow$ better in conductivity due to absence of ^{29}Si and ^{30}Si which scatter the heat carrying phonons and then reduce mean free path.

This isotope has a better conductivity below 100K with peaks of 10 orders of difference at 20K.

Performance and Comparison



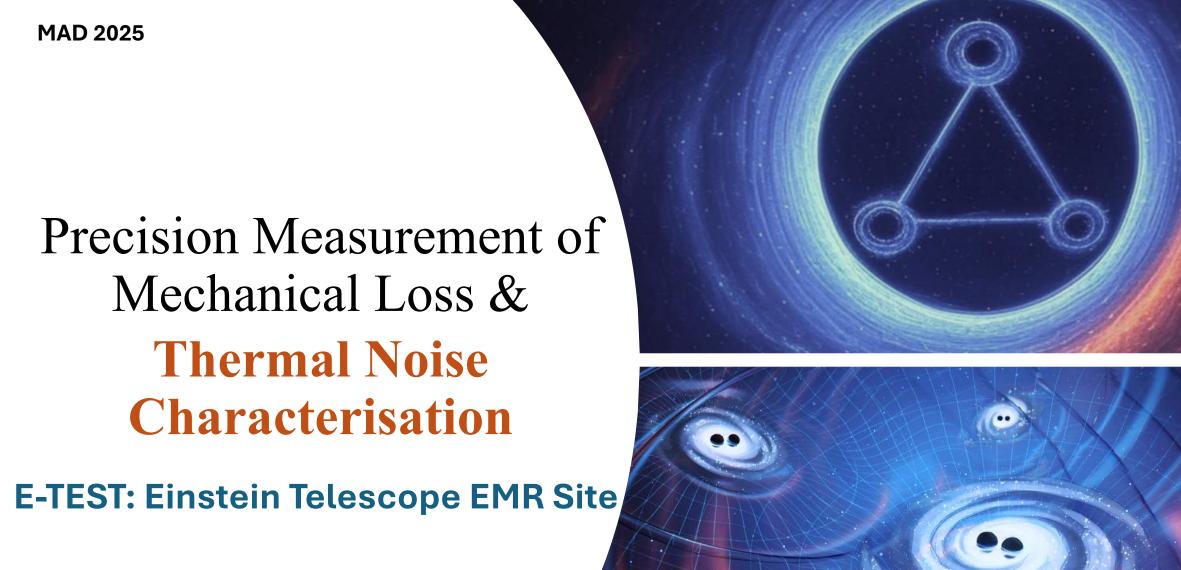
The Compressive solution



Pro	Cons
Better performances	Centre of percussion effect and beam resonance
Easy mounting or disassembling	No recoil mass -> New control solutions must be developed
Good heat extraction thanks to large cross sections	We have to use isotope for flexure to obtain those results

Ref [3]

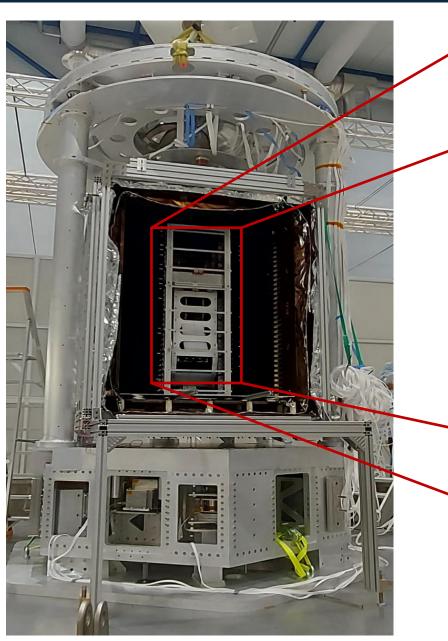
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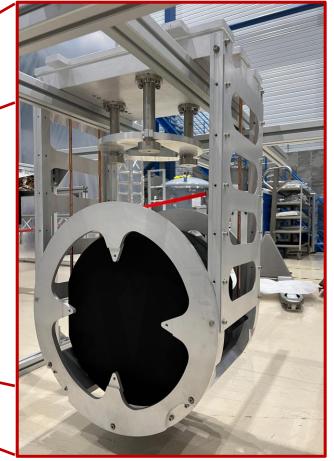


Hemendra Singh

Precision Mechatronics Laboratory - ULiege https://www.pml.uliege.be

2. TEST MASS (First Run:2023)





2023: 1st Run: Dummy Test mass

- •CuCrZr Suspensions
- Aluminium ears attached to TM
- Black painted finish

2. TEST MASS (Second Run:2025)



- Monocrystaline (Silicon)Magnetic Czochralski Process
- Diameter: 45 cm
- Mass: 90 kg





Additionally,

- Mid-tier mass, Cylindrical,
 Ø4.27 cm, 3 cm, ~100 g
- 2. Intermediate mass, Cylindrical, Ø10 cm, 10 cm, ~1.83 kg

Meeting specific minimum
Requirements such as
Roughness <2 nm RMS, Flatness λ/4,
Parallelism <30 μrad, ROC ∞ (Flat) etc.

Ref:SINGLE CRYSTAL Silicon database(ET_docs)

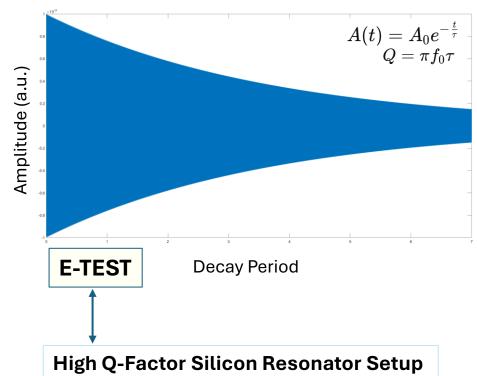
- Diameter: 45 cm
- Thickness ~ 17 cm



3. Mechanical Loss Measurement

Traditional Q- Measurement Method

Monocrystalline Si @ cryo → ultra-high Q, long ring-down!



- Non- Contact Cool Down and Actuation
 (@resonant frequency) of the Test Mass (Si)
- Minimal damping, Lower Thermal Noise!!

Why PLL?

- Ring-down too slow for Silicon
- Faster, Real-time tracking of Resonance, Continuous measurement, no waiting for decay.



Challenges: Non-Contact Method

- properties

 Development of ESD

 approach and analysis of

 Eddy current generation,

 unpredictable electric fringe

 interactions due to

 semiconducting properties
- Integration with Phase-Locked Loop (**PLL**)
- Compatibility with cryogenic operation

Q v/s Temp relationship!!

Temperature Measurement (Non-contact Method)

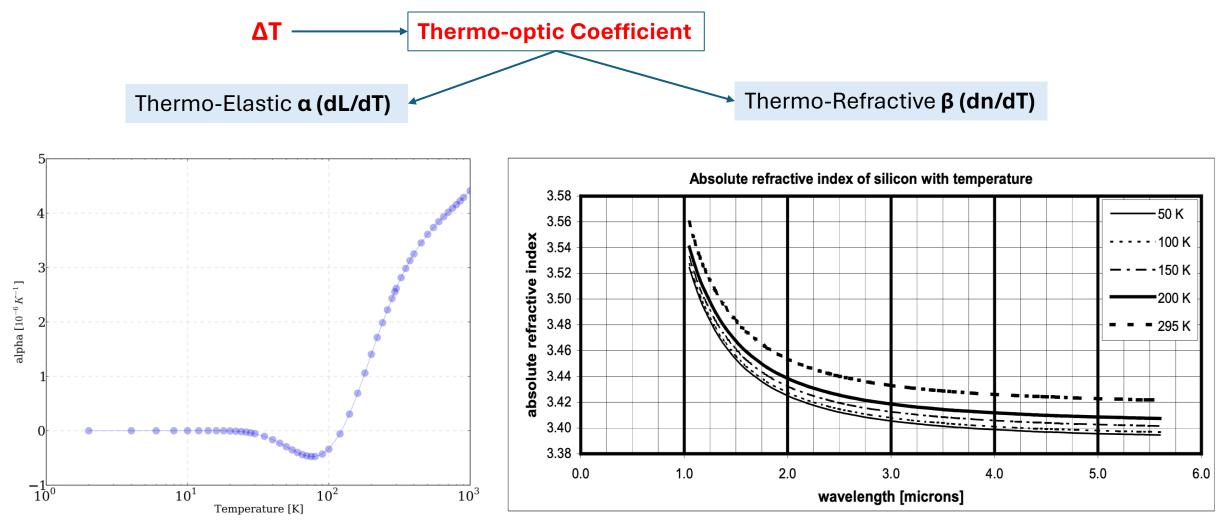
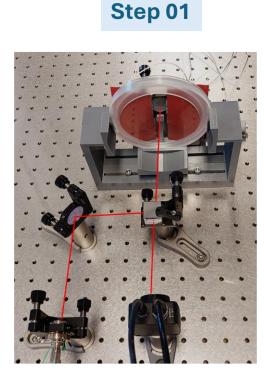
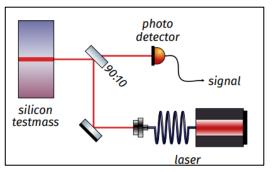


Fig: CTE of Si as function of T

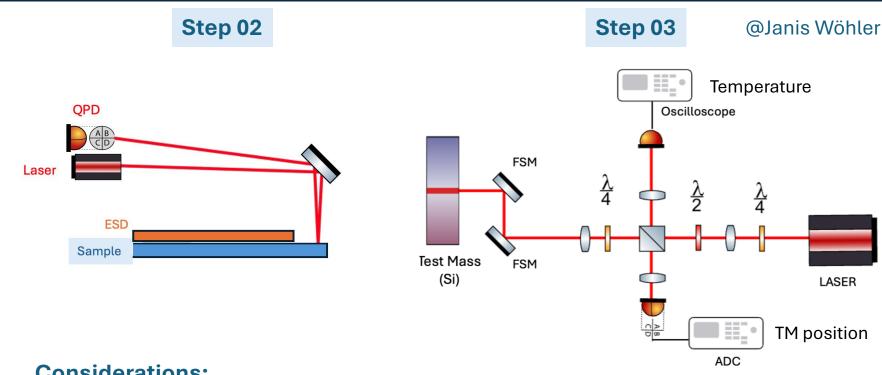
Fig: Measured absolute refractive Index of Silicon as a function of wavelength for selected Temperature

Experimental Framework: Temperature Measurement





OPL $\rightarrow \Delta T \rightarrow \Delta L \& \Delta n \rightarrow$ Fringe shift



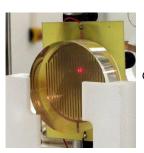
Considerations:

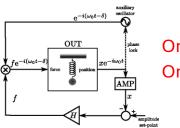
- Effects of ground motion
- LASER (Wavelengths: 1550 nm vs. 2000 nm)
- Scalability



Summary

Quality Factor (Q) Measurement

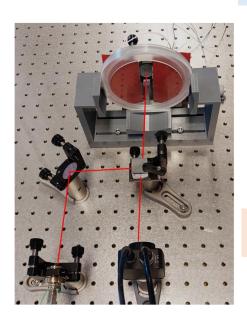




- Study AC, DC, and AC+DC Current effects
- Ongoing
 Fused silica & Silicon samples
 - Apply Phase-Locked Loop
 - ☐ Cryogenic testing



Temperature Measurement



- \Box Fringes $\rightarrow \alpha \& \beta$ (predict thermo-optic coefficients due to $\triangle OPL$) Ongoing
 - ☐ Laser stabilization, Wavelength absorption & Thermal Gradient (1550 nm vs 2000 nm)
 - ☐ Final Optical Setup

Integration

☐ Real-time Q vs T monitoring

E-TEST

(2026)

Mechanical Dissipation in Maraging Steel at Room Temperature and Low Frequency









Matteo Baratti⁽¹⁾⁽²⁾ matteo.baratti@phd.unipi.it











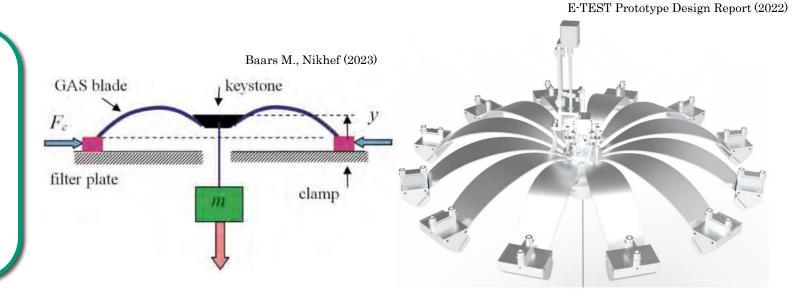
A. Basti⁽¹⁾, R. De Salvo⁽³⁾⁽⁴⁾⁽⁵⁾, F. Fidecaro⁽¹⁾⁽²⁾, F. PODena Arellano⁽³⁾⁽⁶⁾⁽⁷⁾, M. Razzano⁽¹⁾⁽²⁾

(1) INFN, Sezione di Pisa; (2) University of Pisa; (3) California State University; (4) University of Sannio; (5) INFN, Sezione di Napoli; (6) University of Guadalajara; (7) Institute for Cosmic Ray Research

ET-LF Vertical Seismic Attenuation

Geometric Anti Spring (GAS) filters to attenuate vertical seismic noise

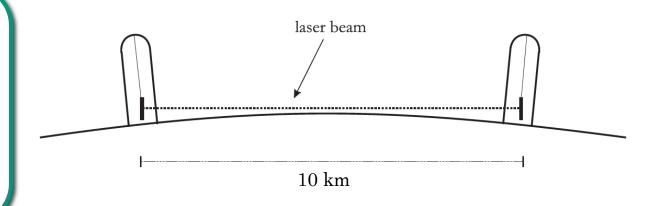
- Used in Virgo and KAGRA detectors
- Components under high mechanical stress → Maraging steel
- Very effective attenuators, but generate their own thermal noise



The vertical direction is not perpendicular to the interferometer direction due to Earth curvature

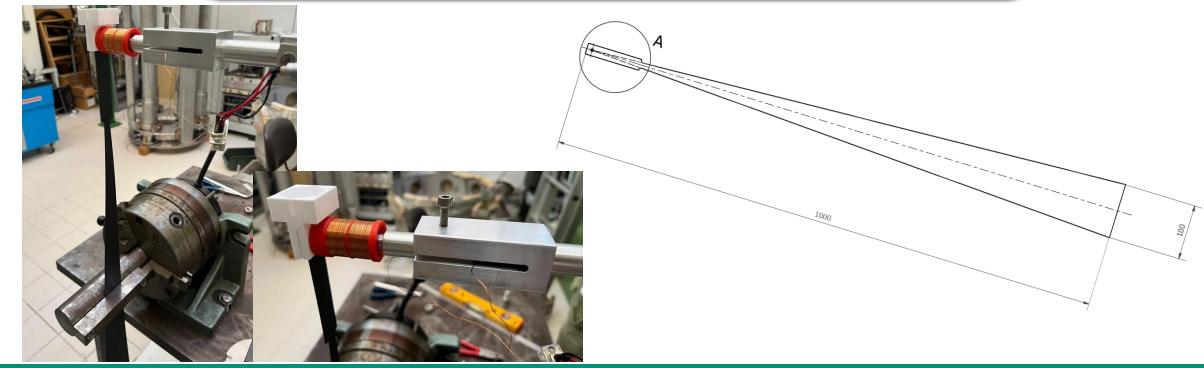
The minimum projection factor for four independent test masses is: $h = 1.57 \times 10^{-3}$

Thus, any noise in the vertical direction has a component that directly affects ET-LF sensitivity

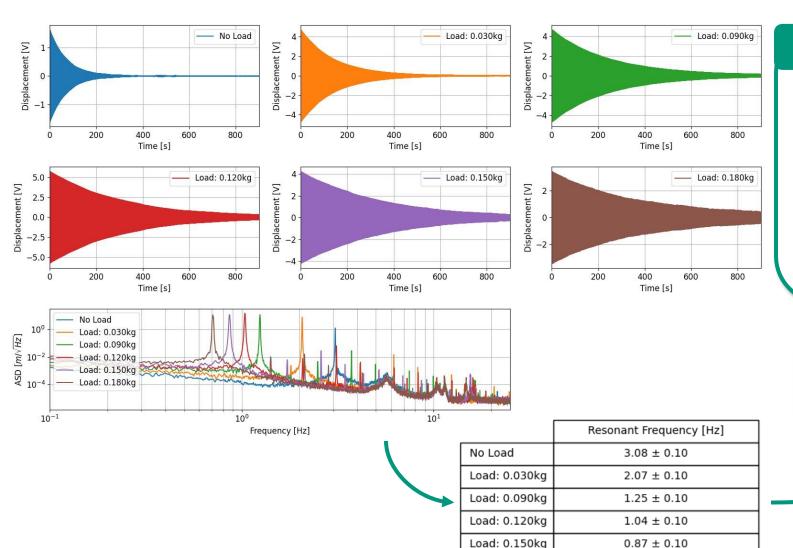


From Calculations to Laboratory

- 1. Goal: assess if the real contribution to the thermal noise of GAS filters is as expected from calculations
- 2. Method: measure the quality factor of a maraging steel blade in the frequency region of our interest
- 3. Experimental Setup: a purpose-built maraging steel blade, at room temperature and in free air, initially standing up therefore under no significant stress



Oscillation Measurements



Measurements strategy

- Three different blade lengths: 200mm, 300mm, 400mm
- Fixed the length, different loads are applied on top: from 0g to 180g
- Data taking 15 minutes long to measure at least two lifetimes decay

From spectrum analysis we get the resonant frequencies f_0

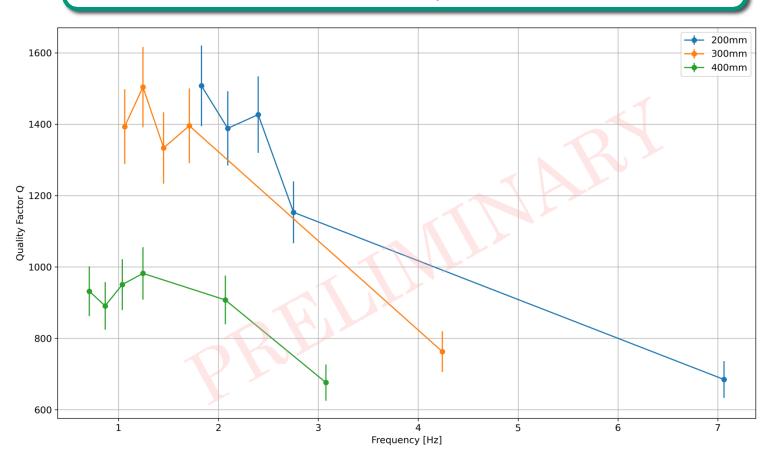
 0.71 ± 0.10

Load: 0.180kg

Quality Factor vs Resonant Frequency

Given the resonant frequency f_0 and the decay constant γ , it is possible to calculate the blade quality factor:

$$Q = \pi \frac{f_0}{\gamma}$$



The quality factor as a function of the resonant frequency shows a strange behavior, common to the different blade setups

So far, we can't explain this behaviour

Many possible different causes are
being investigated



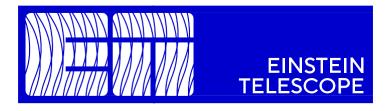
- Inverted pendulum behaviour may affect *Q*?
- Clamp losses?
- Air friction?

Sapphire-Based Suspension at ARC-ETCRYO Laboratory Ongoing Test Campaigns

Van Long Hoang, Eugenio Benedetti, Emanuele Tofani

Materials for Advanced Detectors 2025 (MAD25)

Oct. 6-7, 2025 Berlin





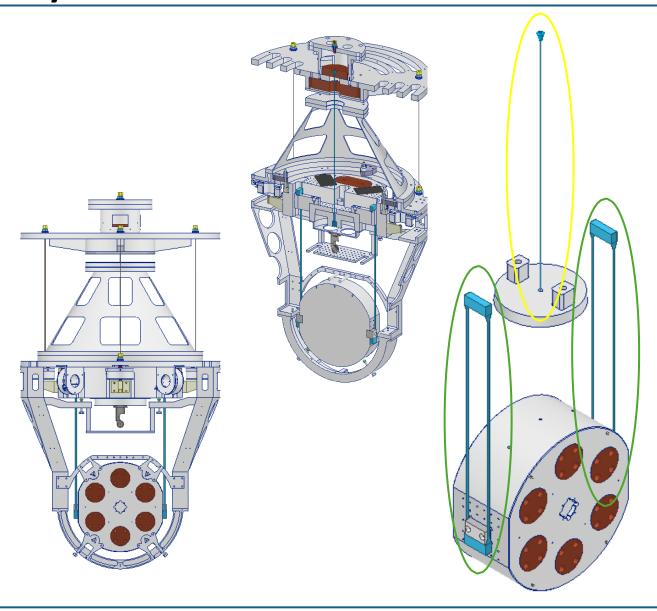


Payload in ARC









Payload total weight ~ 500 kg

Marionette weight ~ 125 kg

Mirror weight ~ 125 kg

Two main sapphire suspensions:

- Marionette suspension
 - Mirror Suspension

First dummy test mass in ARC-ETCRYO is made in aluminum (and copper weights)

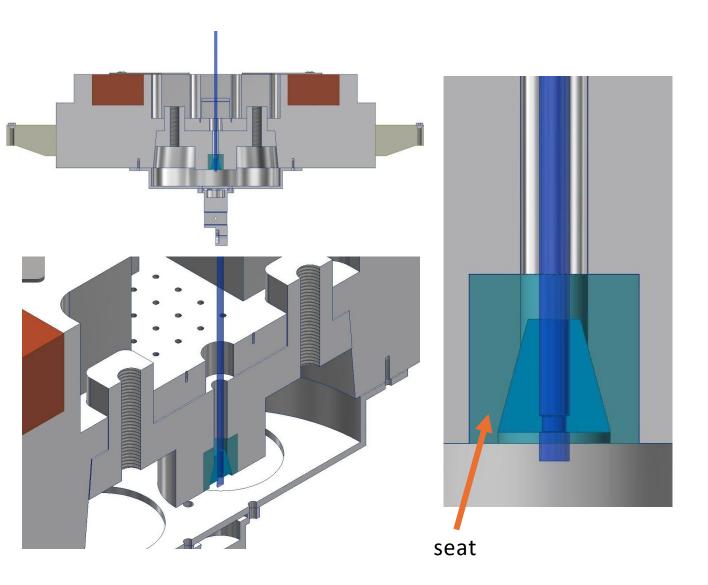
In the future we hope to envisage a sapphire mirror (when technological readiness level is high)

Marionette Suspension









Two sets of **half sapphire cones** *interlock* a single **sapphire rod**.

This system *locks* in place the marionette with respect to the platform, **supporting 250 kg** (marionette + mirror)

At the marionette level, the lateral surfaces of the cones impinge on a sapphire «seat», so that heat exchange is maximized

Length: 870mm

Outer diameter: 5.4 mm

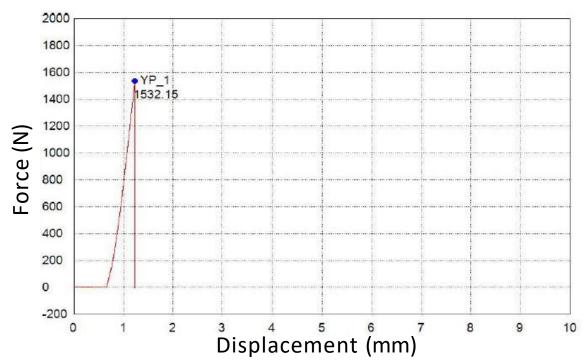
Pull test results







Kyocera Sample result



Failure surfaces of the sapphire sample by kyocera





This particular fracture geometry inspired us for further crystal analysis

Second generation cone/rod system (toothed) gave better results, but not good yet.

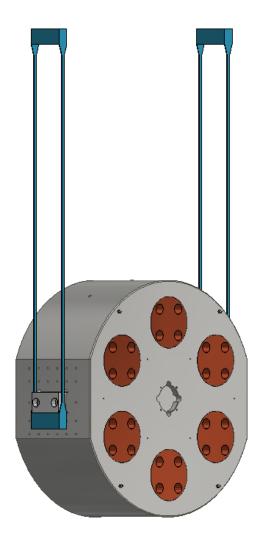
- **Higher number of samples are needed** → statistical distribution of the results
- Need to improve design of the system with production engineers to decrease stress intensification

Mirror Suspension









Two ribbon-like suspensions

Length: 760 mm Thickness: 1 mm

Manufacturing limit for this shape and length

We are studying two different approaches:

- HCB bonding (sodium silicate)
- Monolithic

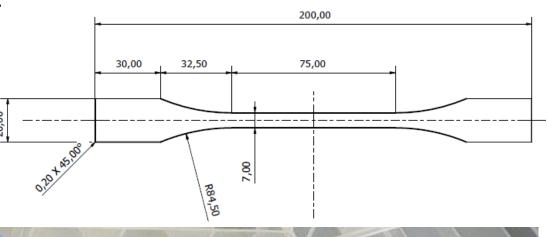
Test to be performed:

- Q test → Mechanical quality factor
- Pull test → Strength

Why Ribbon shaped?

Low thermal noise purposes

Cumming et al. Silicon mirror suspensions for gravitational wave detectors. Classical and Quantum Gravity. 31. 5017-. 10.1088/0264-9381/31/2/025017.



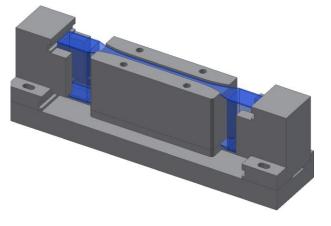
HCB for ribbon sample

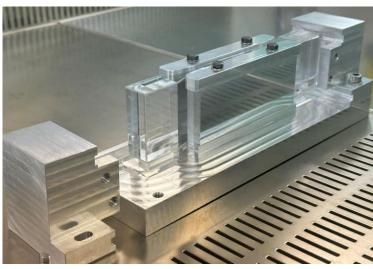






First Generation Jig for Ribbon Bonding



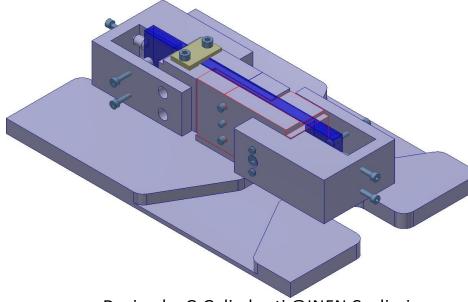


Jig design driving parameters

- Sliding components
- Parallel faces to ensure low disalignment
- Removable components to ensure extraction
- Peek tips to ensure positioning



Second Generation Jig



Design by G.Galimberti @INFN Cagliari

This new design (still under construction) ensures:

- Better cleanliness
- Better ribbon positioning
- Safer and more fluid extraction

Preliminary shear tests







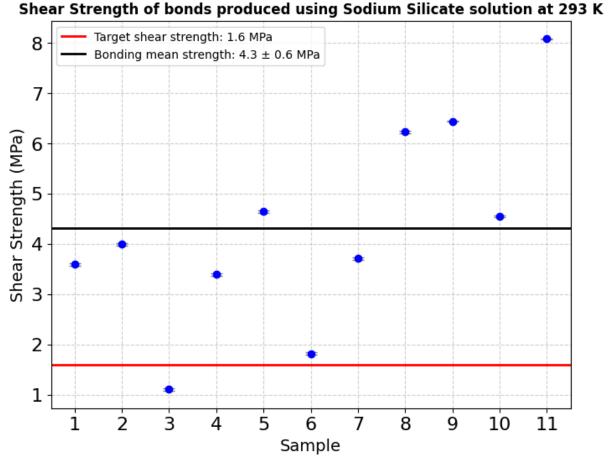
To study how our HCB would perform in our facility, we first decided to bond 3 sapphire blocks (equal to the size of the block sustaining the ear of the mirror).



2 different jis were used (3D printed & aluminum)



3 point bending setup



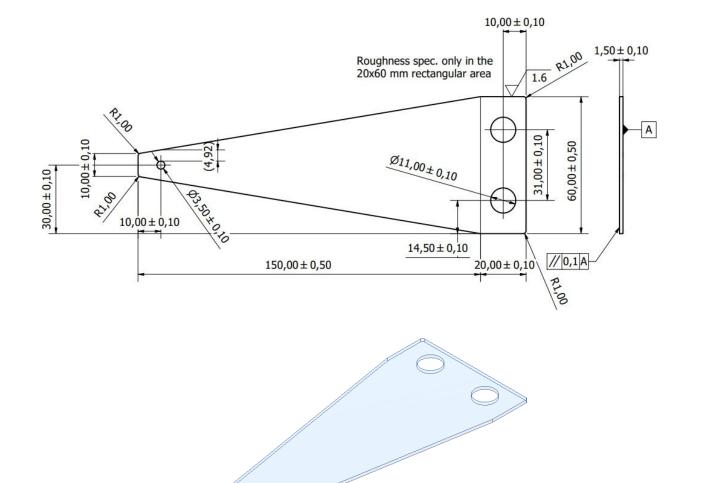
Thanks to Benedetta Kalemi for this measurements

Sapphire Blade









We are also investigating the manufacturing of Sapphire Blades

To be implemented in a vertical vibration isolation system

Bending stress on such a geometry and material will surely end up destructively, so test setup must be well designed

Conclusions







At Rome, in ETCRYO Lab we are working on sapphire systems for the ET-LF cryogenic payload.

- Sapphire suspension for the marionette
 - Pull test on the locking system
 - Design improvement on crucial parameters
- Sapphire suspension for the mirror
 - Two different approaches: HCB and monolithic
 - Design improvement on the bonding jig
 - Q test for mechanical quality factor
 - Investigating main problem on the setup and resonance frequency
 - o Pull test
- Mechanical test machine
 - Design improvement on test jigs to avoid misalignment on the samples
- Sapphire blades
 - Ongoing design
- Crystal studies on broken samples
- Purchase campaign ongoing
 - Statistical measurements
 - According to FEM analysis and first test results, following design improvements









Sapphire suspensions for KAGRA and ET with low loss jointing techniques

MAD Workshop Berlin 2025

Jennifer Docherty*, Jack Callaghan, Sarah Dugmore, Giles Hammond, Karen Haughian, James Hough, Russell Jones, Gregoire Lacaille, Iain Martin, Mariela Masso Reid, Peter Murray, Munetake Otsuka, Sheila Rowan, Andrew Spencer, Claire Wilson, Alan Cumming

WORLD CHANGING GLASGOW *j.docherty.2@research.gla.ac.uk

Institute for Gravitational Research
University of Glasgow

A WORLD TOP 100 UNIVERSITY



1.6 mm

Sapphire welds

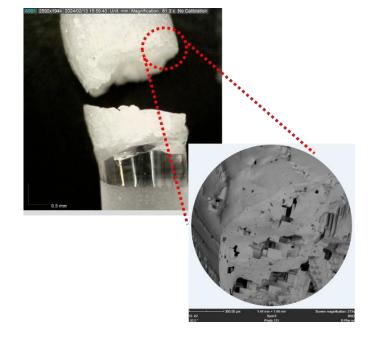
1 mm

Laser

polished

- 100+ welds in total completed
- Smallest diameter: 425 µm
- Largest diameter: 1.6 mm
- Investigated surface quality
- Ability to repair/reweld repeatedly

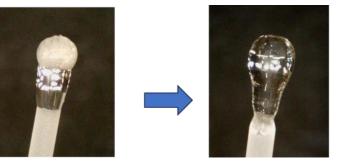


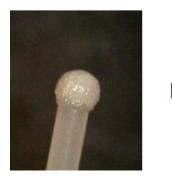












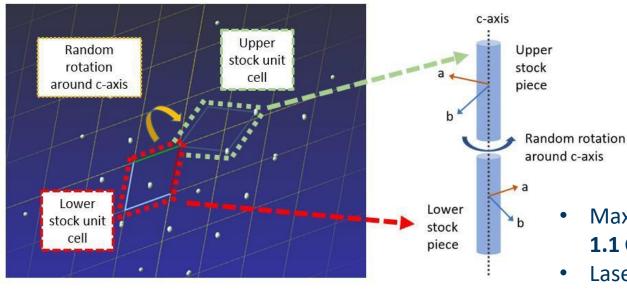


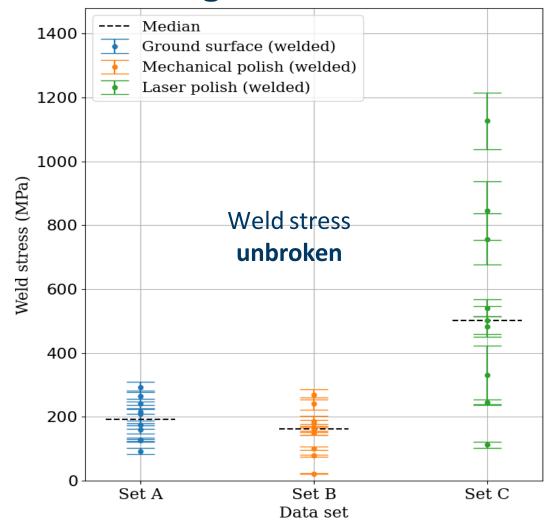




Crystallography and tensile strength

- In both welded samples and grown fibres, it was shown that the c-axis orientation was maintained in the joint region, with an arbitrary rotation of the a and b axes
- Crystalline weld region limited to ≤200 μm





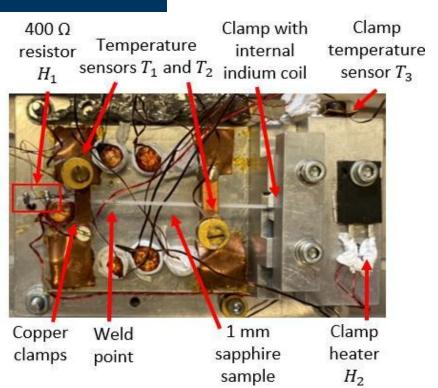
Maximum stress observed in a laser polished and welded sample: **1.1 GPa, unbroken**

Laser polishing shown to increase tensile strength up to three times when compared to ground and mechanically polished samples

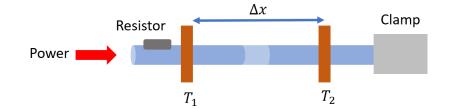


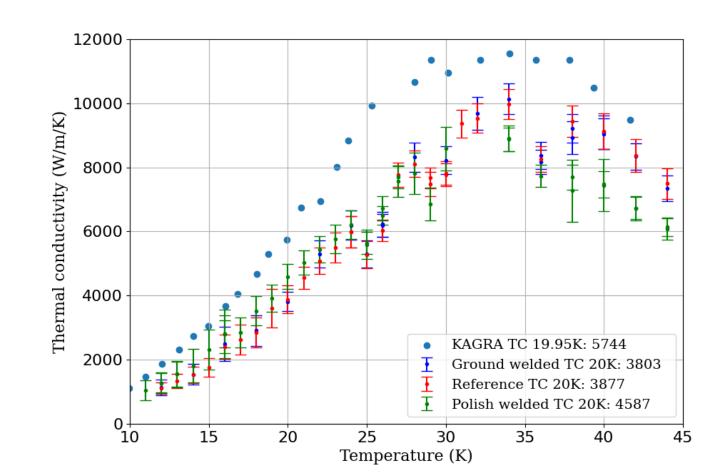
Thermal conductivity

Research undertaken with Dr. Karen Haughian and Dr. Mariela Masso Reid



- Measurements of three samples down to 13 K using steady state method
- No appreciable difference between welded and unwelded sample
- Difference to KAGRA curve thought to be due to purity levels in base sapphire

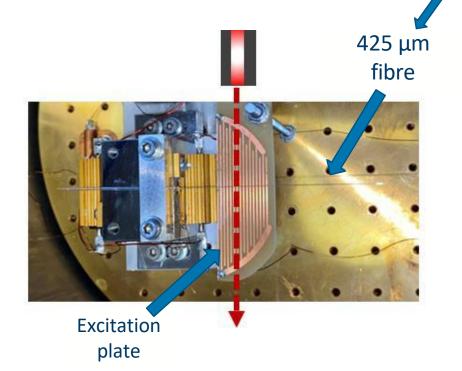






Mechanical loss

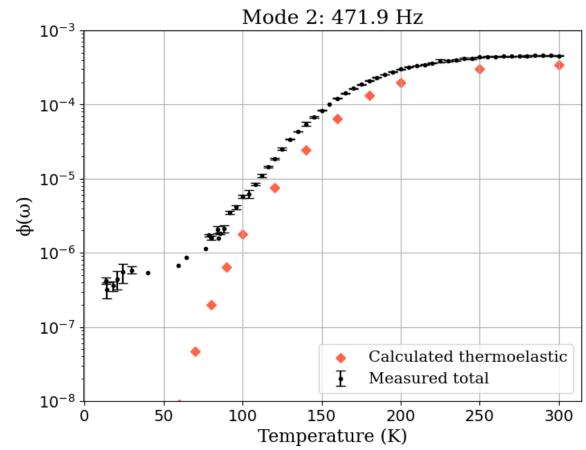
- Measured down to 13 K for six resonant modes
- Using welded 425 μm fibre to 1 mm rod





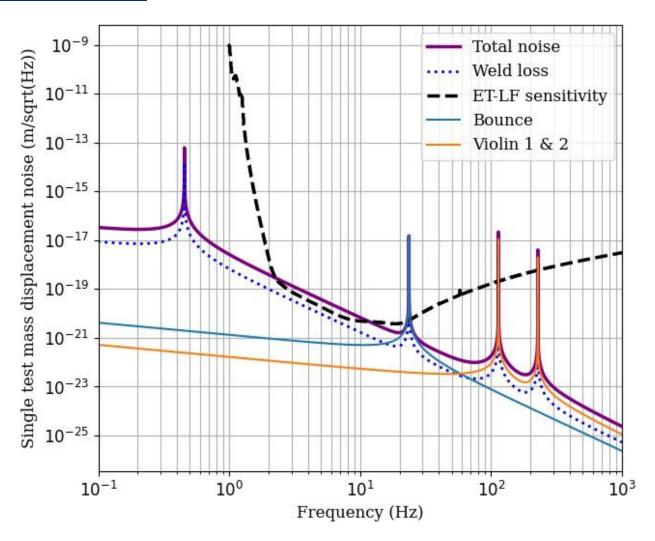
Research undertaken with Dr. Peter Murray, Dr. Iain Martin and Dr. Alan Cumming

Lowest measured loss average: 3.2×10^{-7}





Suspension thermal noise modelling in ET

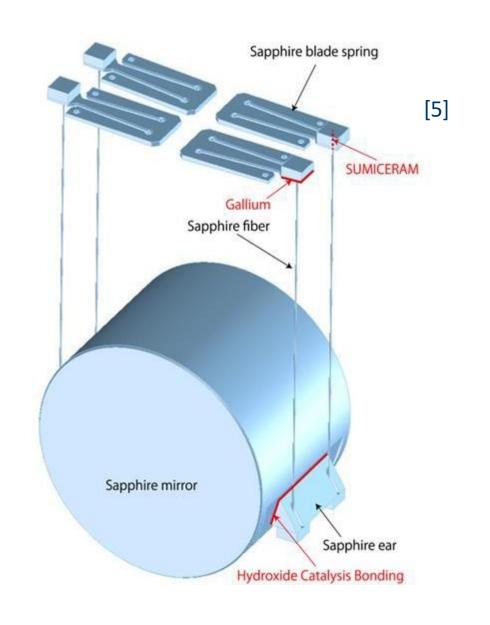


- Includes measured loss, with estimated decoupling
- Model of 1.52 mm diameter fibres with 5 mm stock ends compared to current ET-LF design curve [4]
- Total noise is already approaching design curve without fully optimising weld loss



KAGRA Suspensions

- 4 x sapphire fibres of 1.6 mm diameter and 350 mm length
- Attached to 20 x 20 x 10 mm nail heads using SUMICERAM alumina bonding agent
- Nail heads bonded to blade springs using gallium bonding





Development of a Silicon Suspension System for the **ETpathfinder**

M. Kühler^{1,2}, A. Bertollini^{1,2}, S. Hild^{1,2}

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Motivation: silicon in ETpathfinder

The ETpathfinder (ETPF) is a cryogenic test facility in Maastricht, aimed at developing core technologies for the Einstein Telescope, a future thirdgeneration gravitational wave observatory. The facility utilizes a high-sensitivity (< $1 \times 10^{-18} \ m/\sqrt{Hz}$ at 10 Hz), 10-meter interferometer prototype to evaluate crucial

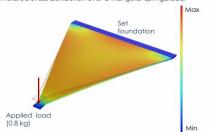


subsystems, focusing on the performance of crystalline silicon test masses and their suspensions under extreme cryogenic operating conditions, specifically aiming for temperatures around 18 K and 123 K [1].

One key component under investigation is a low-noise suspension system designed for cryogenic operation. Due to its low mechanical quality factor and low thermal conductivity at cryogenic temperatures, the so far used material, silica, is not suitable to reach the aimed sensitivity goals [1]. Silicon, therefore, is a strong candidate for use in suspension elements due to its favourable properties at low temperatures, including a high mechanical quality factor, excellent thermal conductivity, and a low thermal expansion coefficient. These characteristics are critical for thermal noise reduction and system stability under cryogenic conditions [2]. To address potential variations in the geometry of silicon suspension wires and further minimise thermal noise, the implementation of silicon blade springs is being explored. We currently use finite element simulations to study different blade designs with a focus on stress distribution, deformation, and eigenfrequencies. Breaking strength measurements for prototypes of silicon springblades are currently planned. Additionally, we present prototypes of silicon-silicon connections.

Springblades

A triangular blade design with 1 mm thickness is currently considered for the first springblade design. Different width and length variations were analyzed using FEA, and the final geometry will be selected based on breaking strength. The target is a first eigenfrequency below 10 Hz. Simulated stress distribution over a triangular springblade:



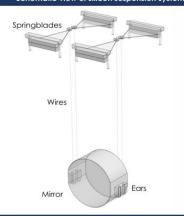
Quadrature cut in a 1 mm thick silicon wafer using ultrashort-pulse laser cutting [3]:



The first prototypes will be fabricated from undoped silicon wafers with [100] crystal orientation using an ultrashortpulse laser cutting process. The wafers have a thickness of 1 mm and are cut into rectangular geometries. The image on the ight illustrates a quadrature cut produced in a 1 mm thick wafer with this laser process

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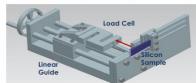
Schematic view of silicon suspension system



Test setup for springblades

Breaking strength will be tested with the setup shown below. The aim is to reach a high strength and to demonstrate reproducibility between samples.

Test setup for breaking strength tests [5]:



Silicon-silicon connections





A cylindrical hole was machined into a silicon block to insert a 1 mm silicon wire, after which the assembly was baked in a nitrogen-rich atmosphere. Future tests will evaluate heat conductance, strength, and mechanical loss. The samples are manufactured by Impex High

References

(1) Expansion of the Syogenic Vehicles of interesting developments of the Syogenic S

[4] Courtesy of Rogier Elsinga, relsinga@nikhef.nl [5] Courtesy of Mathijs Boars, m.baars@nikhef.nl

Nik hef

Towards Reliable Bonding of Sapphire and Silicon II



Silicon Welding Updates:

RayVen Dr. Cella Millon, Dr. Michael Müller

Bonding of a Silicon Fiber by Float Zone (FZ) method



100 kHz, 3.5 W, 35 uJ, 1.5 ps

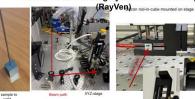
f = 10 mm, w, = 2.5 mm (radius

Velocity 2-20 mm/





Trials to Si-Si Welding by Ultrafast Laser 2.1µm





M.Sc. Philipp L. Maack, 8. Sc. Jonas Wehner, M. Sc. Simon Schenk, Dr.-Ing. Marvin Schuleit Dr.-Ing. Aleksander Kostka Prof. Dr.-Ing. habil. Andreas Ostendorf

Machine for testing of tension stress. INSTRON-5581, load up to 100 kN. Metal holder for cubic ends was produced. Cuprum layers were used to uniform load to the cubic surface. The cuprum parts in the metal holder for cubic ends were added to solve some misalignment between rod's axis and cubic's axis. The cuprum parts were softened by heat treatment before tests.

Bonding of a sapphire fiber by

Melting in a Furnace / USP Laser Welding +Tensile Strength Tests on Sapphire Fibers

Bonding of a sapphire fiber by melting in a

furnace (Inst. Of Single Crystals)

CLAT RUB

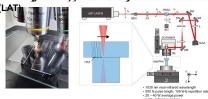


General scheme of infiltration and process observation. 1 - Plates with capillary channels, 2 - Capillary channel, 3 - Dark background for high-contrast observation, 4 - Crystal/molten droplet for infiltration, 5 - - Pedestal for the molten droplet, 6 - Field of view for the observer and





Bonding of a sapphire fiber by Ultrafast Laser Welding









- Tensile testing machine: MTS 858 Mini Bionix II , load up to 2.5 kN, Crossbar speed: 0.5 mm/min. Procedure





determine the welding process. Increasing energy absorption by gold layers?

The above results were achieved with the support of Central Innovation Program for small and medium-sized enterprises Funding Nr. EP201456 and Dutch National Institute for Subatomic Physics (Nikhef)

Advancing electrochemical micromachining technology for new and difficult-to-cut materials









Poster Session



6 Oct 2025, 14:05

(§ 10m

♀ Leibniz-Insitut für Kristallzüchtung (IKZ)

Speaker

Dr Muhammad Hazak Arshad (KU Leuven)

Description

Electrochemical micromachining (ECM) is a non-contact and athermal process that can machine electrically conductive materials through anodic dissolution in the presence of an electrolyte and applied voltage governed by Faraday's law of electrolysis. The absence of mechanical forces and thermal damage make ECM especially suitable for machining advanced materials, regardless of hardness, while preserving surface and subsurface material properties. This is critical for ensuring functional performance in high-tech sectors such as aerospace, biomedical, MEMS and precision tooling.

At the Micro- & Precision Engineering Group (MPE) at KU Leuven, the research is focused on advancing both tool-based and jet-based ECM process configurations using custom-built and commercial setups for shaping and surface structuring applications. One of the key research tracks is to develop strategies for machining advanced materials with high precision and surface integrity. The team has also developed in-house a novel hybrid laser-electrochemical machining (LECM) technology to deliver coaxial microsecond pulsed-electrochemical and nanosecond pulsed-laser process energies simultaneously to the machining zone, to enhance reaction kinetics, material removal rates, precision and surface quality.

These processes have shown promising results on a range of material classes, including superalloys, cermets/carbides and tool steels. These capabilities make ECM an interesting technology to explore further for machining monocrystalline silicon to support the machining/finishing of the suspension system of the Einstein Telescope.

Author

Dr Muhammad Hazak Arshad (KU Leuven)

Co-authors

Prof. Krishna Kumar Saxena (KU Leuven)

Prof. Dominiek Reynaerts (KU Leuven)

Cooling away the absorption - Silicon mirror development for 🙎 🕒 📋 future gravitational wave detectors





Poster Session





(§) 10m

♀ Leibniz-Insitut für Kristallzüchtung (IKZ)

Speaker

Janis Woehler

Description

Silicon is the substrate material chosen for future gravitational wave detectors such as ET mainly because of the low optical absorption together with a high mechanical quality factor. To optimize the coatings deposited on these silicon substrates, they have to be annealed to temperatures above 600°C. At temperatures between 450°C and 600°C thermal donors start to form, increasing the optical absorption. A careful procedure consisting of heating and cooling has to be found to minimize the impact of these effects. Furthermore, characterizing and understanding the effect of annealing and rapid cooling on internal stress and related birefringence, as well as resulting wavefront distortions and their effect on the laser beam is essential to

understand and minimize the effect on the detector performance.

Author

Janis Woehler